

Detailed process characterization of carbonated LGADs through Secondary Ion Mass Spectroscopy

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Using high resolution Secondary Ion Mass Spectroscopy (SIMS), the gain layer doping profiles of carbonated FBK UFS2 and CNM RUN 10478 LGADs are evaluated. A combination of $^{55}\text{Cs}^-$ and $^{16}\text{O}^+$ primary ion driven campaigns yield a high sensitivity in the order of $1.35 \times 10^{14} \text{ atoms/cm}^3$ for Boron concentrations along with a precise depth estimation within $\sim 5 \text{ nm}$. For Carbon profile studies, a 62-hour Caesium pre-sputtering protocol is established which, combined with beam parameter optimization, result in an unprecedented sensitivity of $2 \times 10^{15} \text{ atoms/cm}^3$. Through advanced analysis techniques, conclusions are extracted concerning the implantation dose, energy and activation for Boron and Carbon implants. The latter are validated through Monte-Carlo TCAD process simulations, while Boron de-activation on carbon co-implantation is discussed. Finally, using as input the measured dopant profiles, electrical simulations are presented and compared with previously reported laboratory data.

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